

DFEB Methodology Guidelines for Physical Design Engineers

Revision 2.1 November 9, 2009

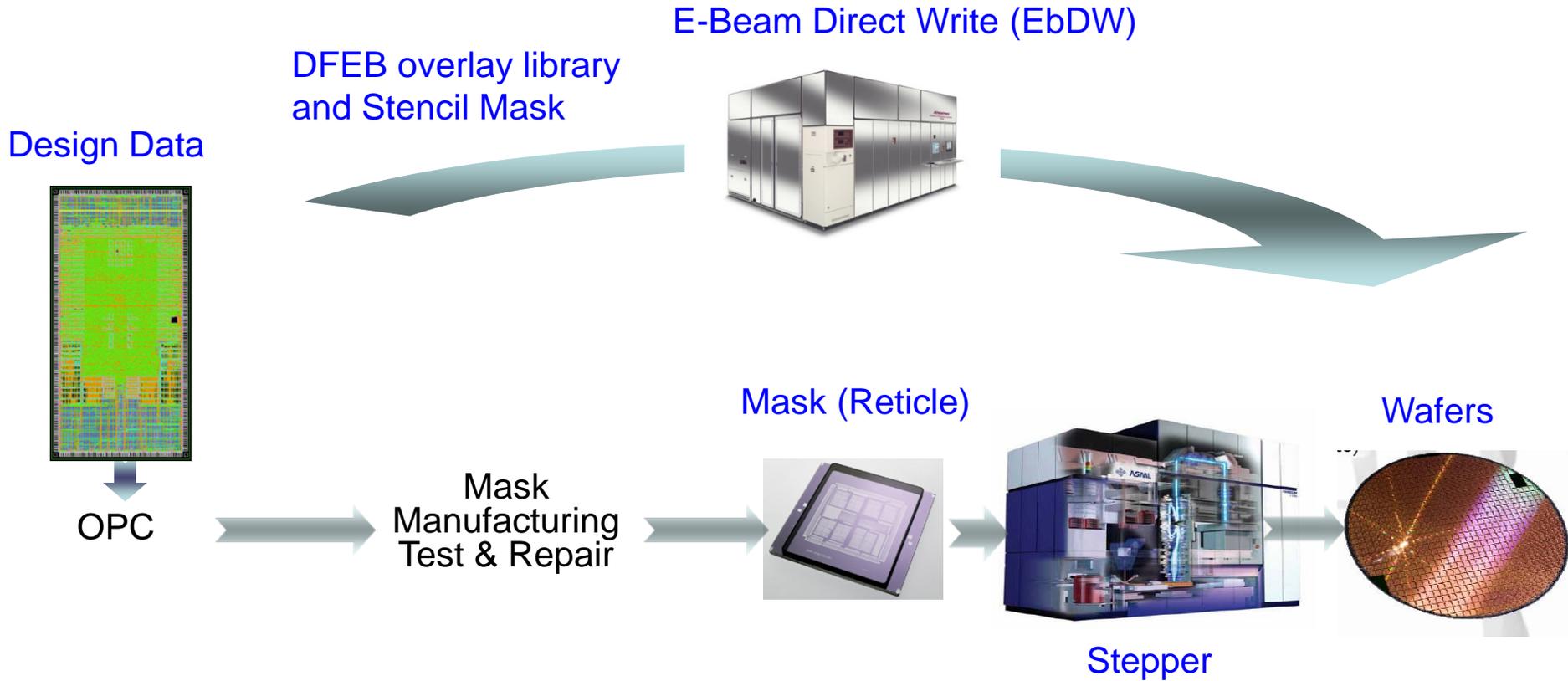
Content



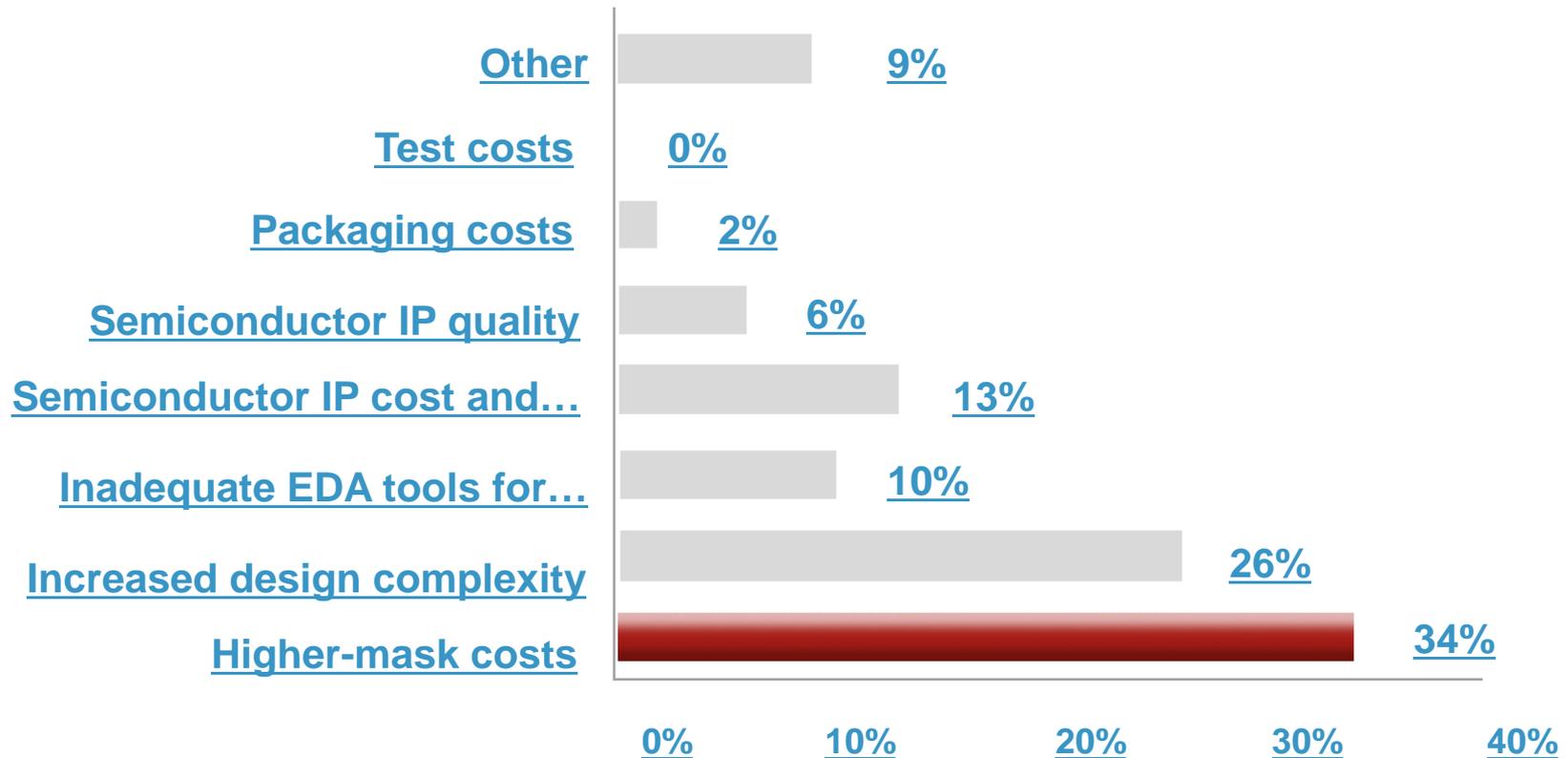
- Design for E-Beam: What and Why
- Shot Count Analysis
- Synthesis Best Practices for DFEB
- Place & Route Best Practices for DFEB

Design for E-Beam (DFEB): What and Why

DFEB vs. Mask Manufacturing Process

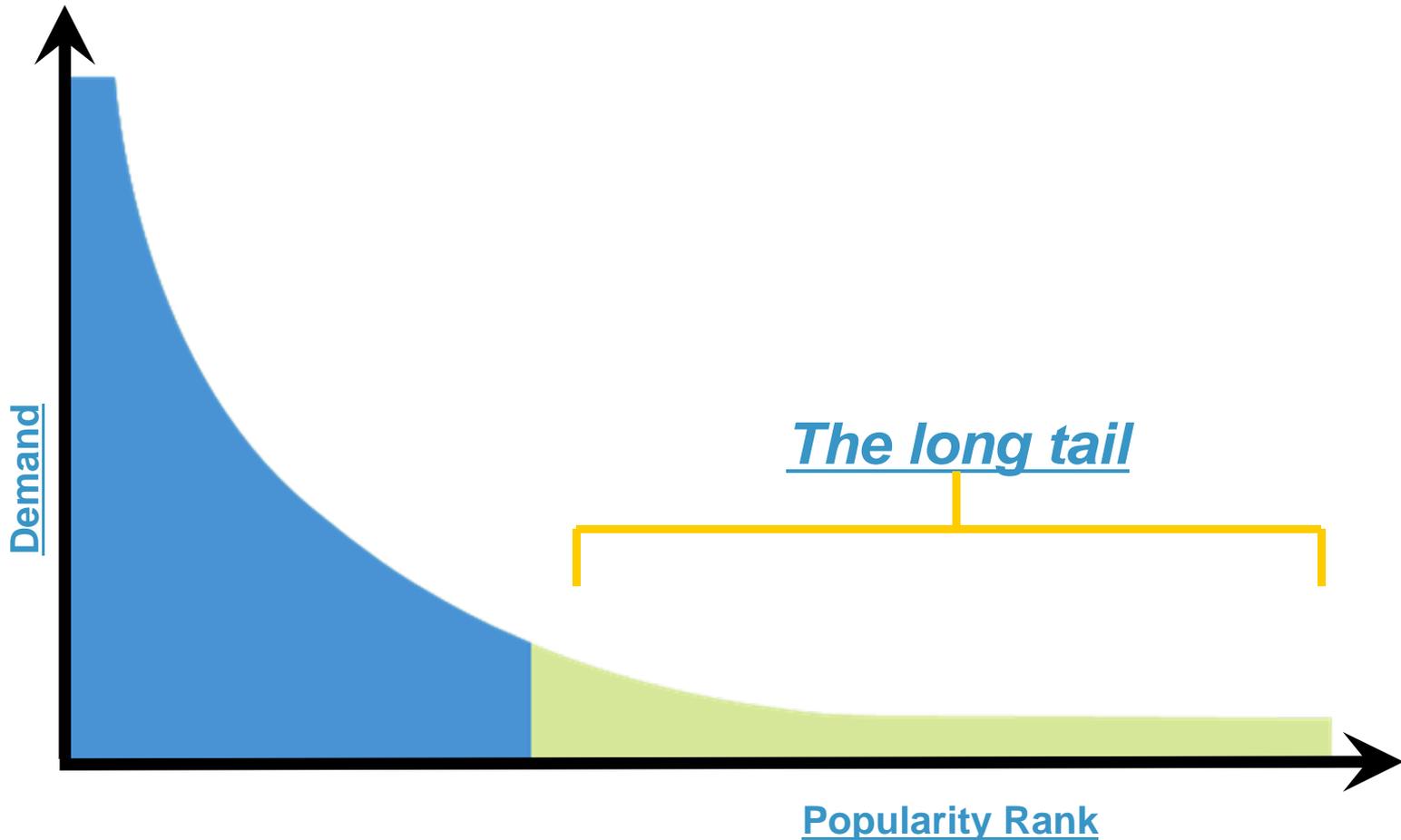


Mask Cost is Top Concern



Source: Global Semiconductor Association (GSA) member survey, December 2007

Enabling the Long Tail of SoCs



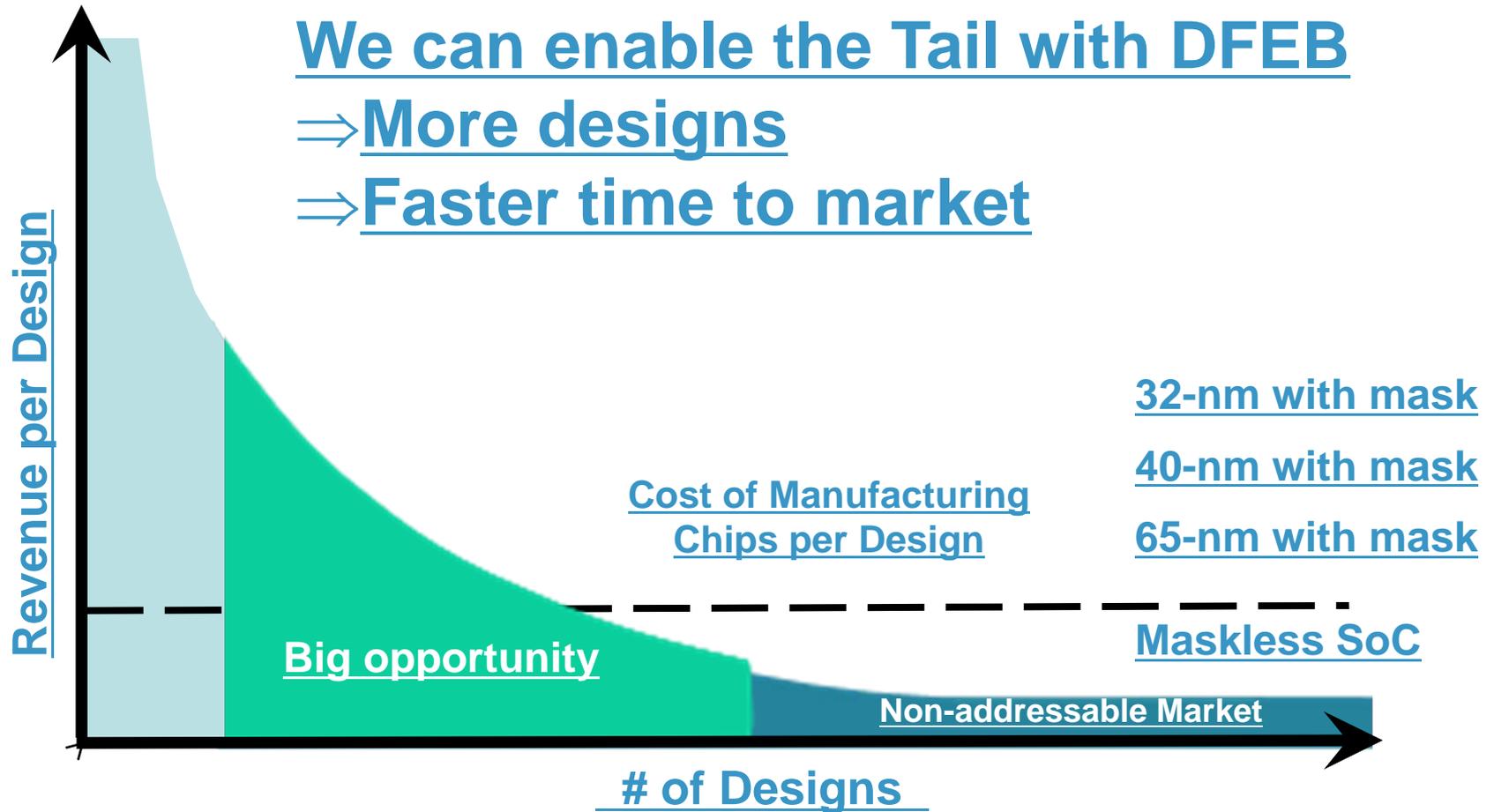
Source: Chris Anderson's "The long tail: Why the future of business is selling less of more"

The Tail is Getting Shorter

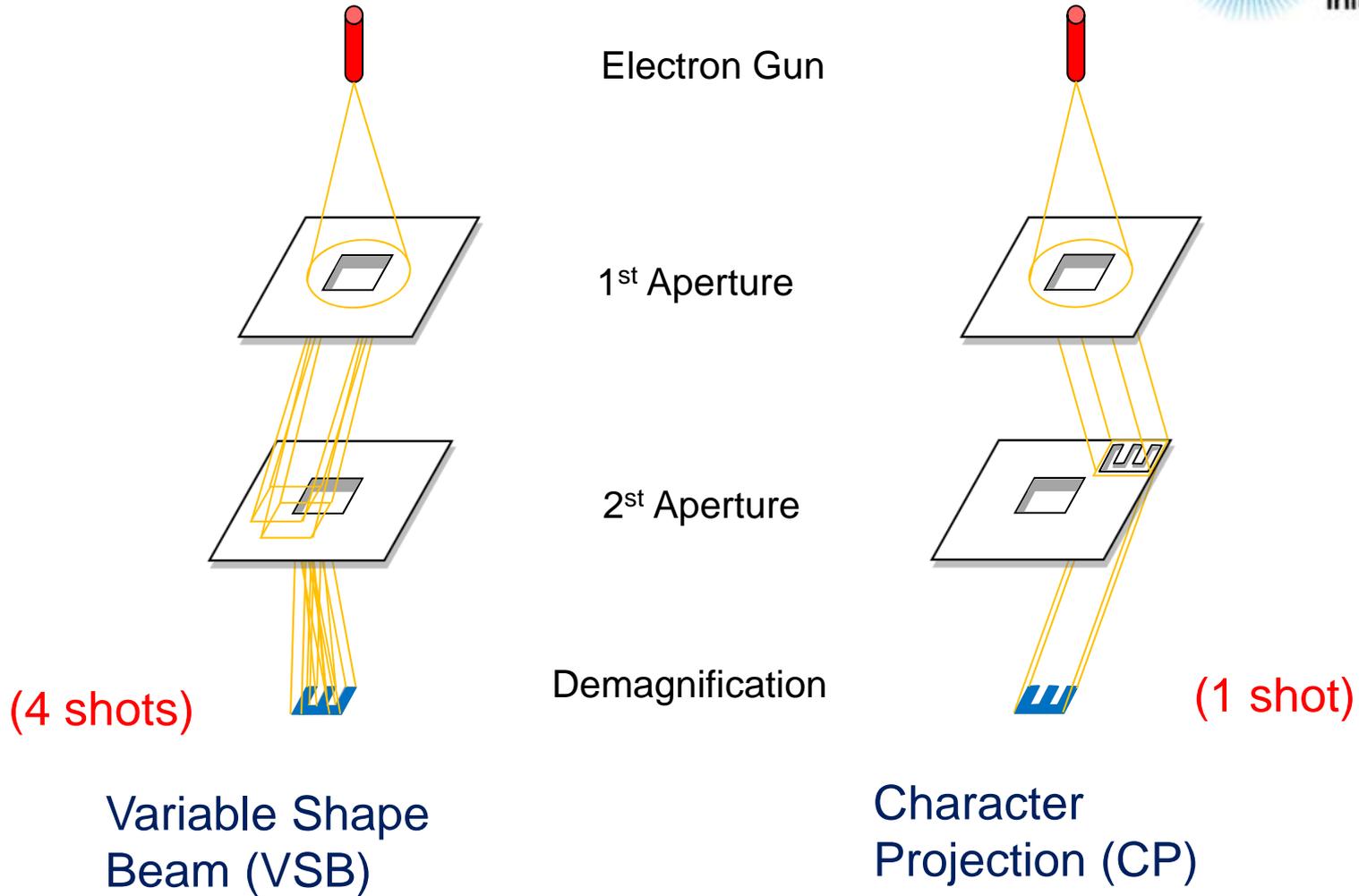
We can enable the Tail with DFEB

⇒ More designs

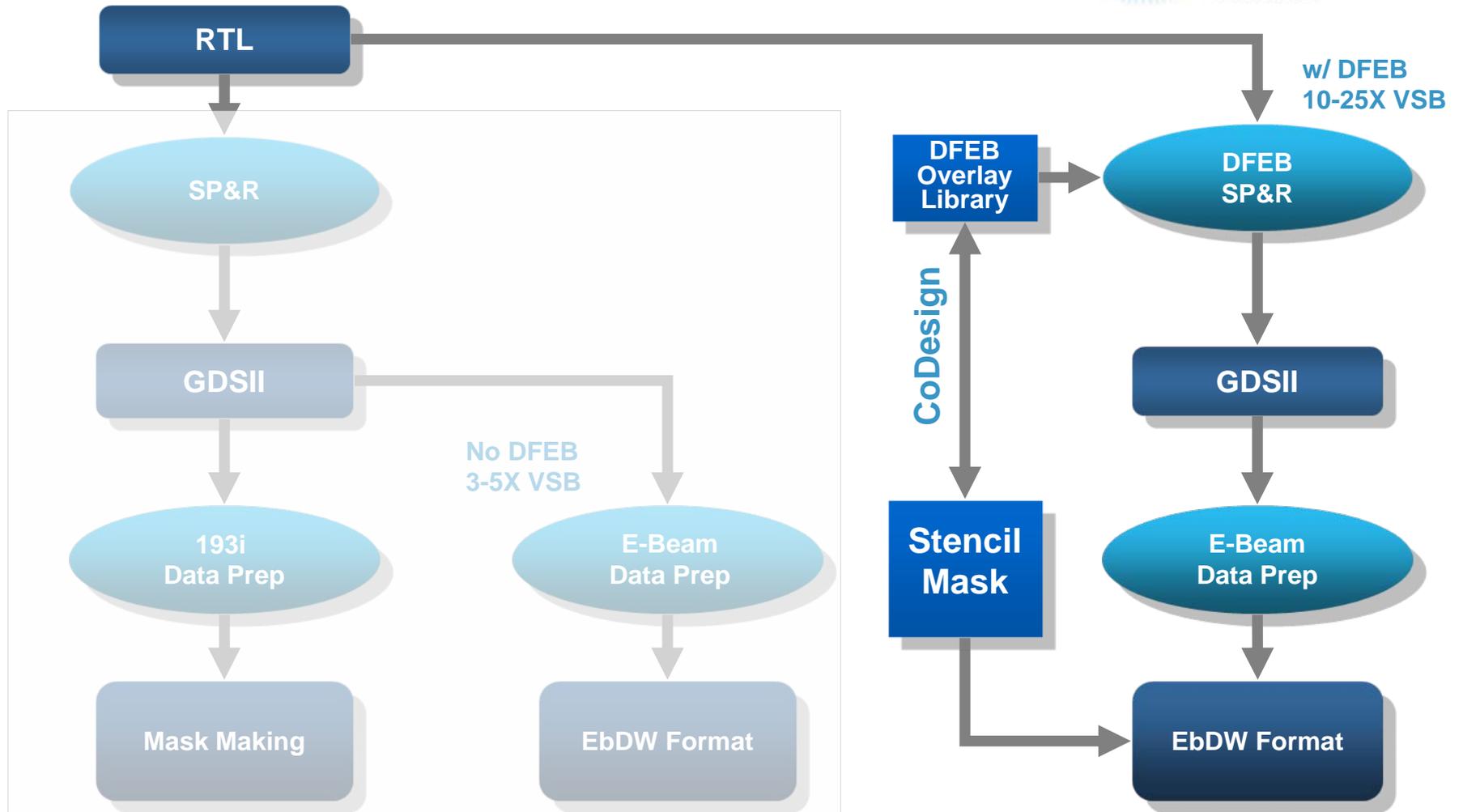
⇒ Faster time to market



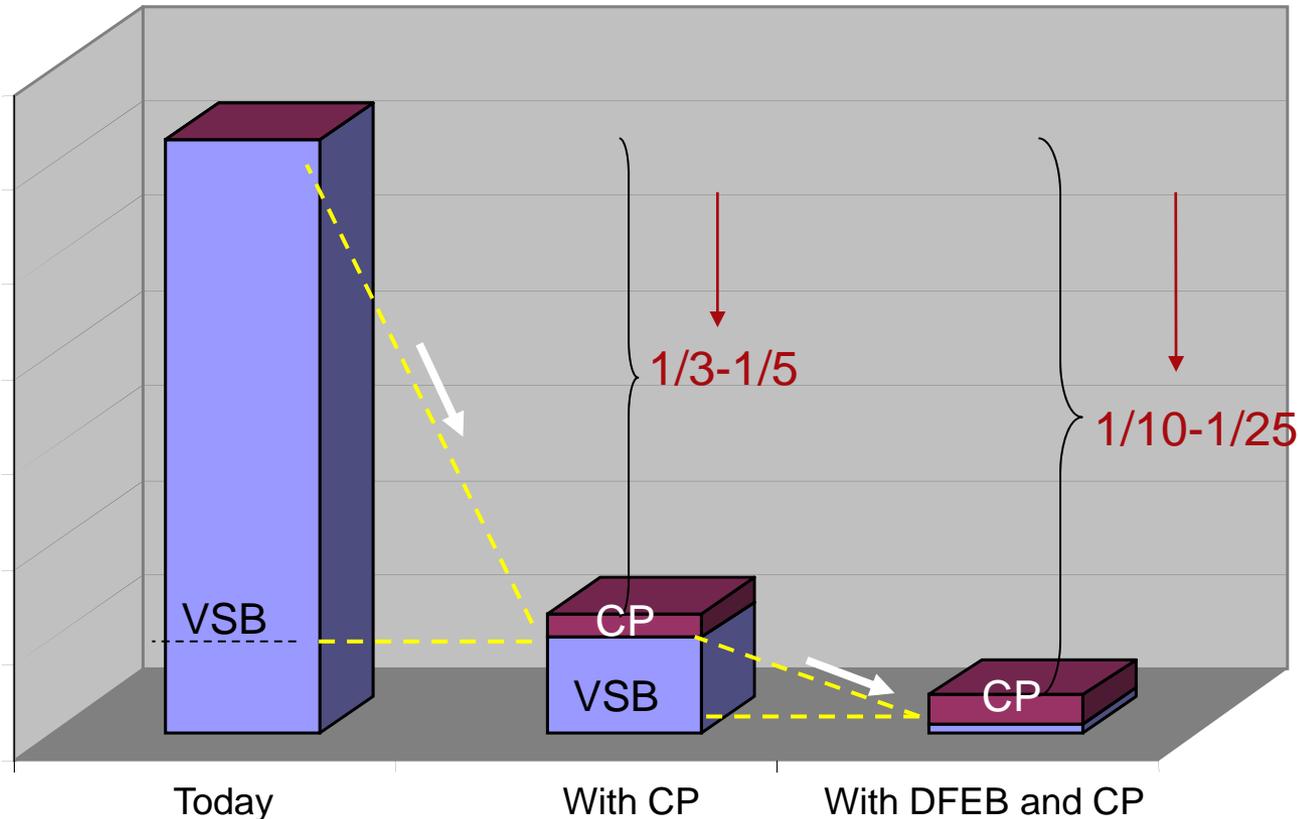
DFEB Uses Character Projection



DFEB Overview



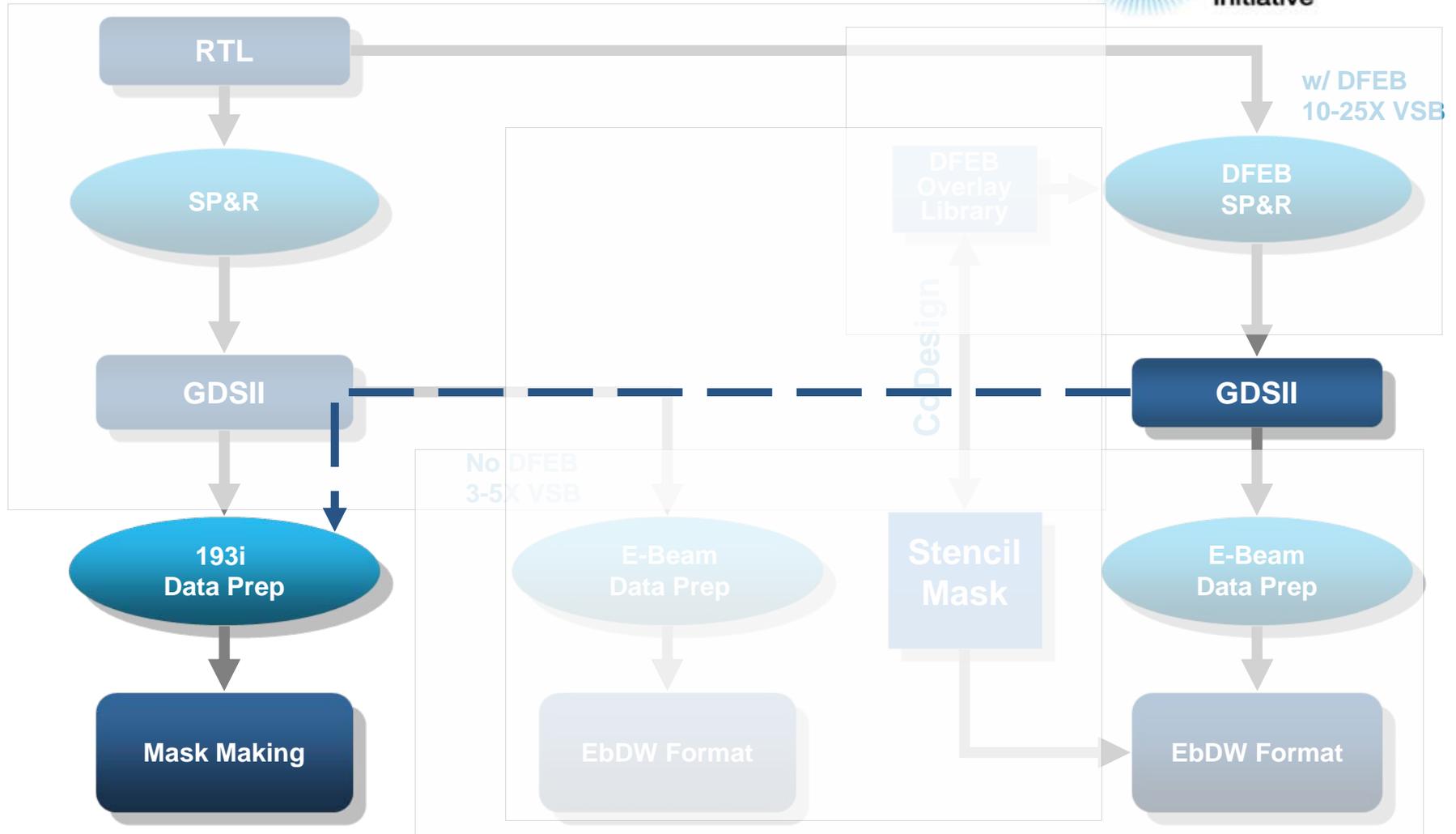
DFEB Increases Throughput by Decreasing Shots



DFEB achieves a 10-25X reduction by:

1. Co-designing the cell library and the stencil mask
2. Optimizing the physical design for CP

DFEB Designs Are Compatible With Mask-based Volume Productions



Shot Count Analysis

Terminology Clarification



- “Generic” flow/steps: Refers to the flow you are already using
- “DFEB” flow/steps: Additional steps or data needed to augment the generic flow for DFEB

Why Shot Count Is So Important



- Generic flow optimizes for area, timing, yield and power
- In DFEB flow, also optimize for shot count
 - Goal is defined at the beginning of the design
- Run shot count analysis at multiple points in the flow
 - Design flow checkpoint
 - Monitor and evaluate the cost of design trade-offs
- Shot count reports are refined in each step throughout the flow

Pre-RTL Shot Count Analysis Worksheet



Pre-RTL Shot Count Estimation		
D2S DFEB Library: 45nm Low Power		
Design Name: DFEB test chip		
Target Area (mm ²): 64.2		
Estimated Gate Count: 24,000,000		
Estimated FlipFlop in Design (%): 10.80%		
Estimated Combo Gates in Design (%): 89.10%		
Estimated Non-DFEB Gates in Design (%): 0.10%		
Total Single port RAM bits: 5,000,000		
Number of 1-port RAM: 60		
Total 2-ports RAM bits: 10,000,000		
Number of 2-port RAM: 6		
Total Number of Custom Circuit (IP): 1		
Estimated Total Area of Custom Circuits (um ²): 240000		
Total number of Port (pins): 794		
Estimated Shot Count Report		
Estimated Area & Utilization		
Estimated core area(mm ²):	58.5943	58.5943
Estimated standard cells area(mm ²):	15.6000	16.2000
Estimated hard macros area(mm ²):	28.3650	30.1150
Estimated pads area(mm ²):	5.6057	5.6057
Estimated Total core utilization ((s+m)/core area):	75.03%	79.04%
Estimated Total cells utilization ((s+m+p)/chip area):	77.21%	80.87%
Estimated Total utilization((s+m+p+fillers)/chip area):	100.00%	100.00%
Estimated Range		
Estimated VSB (OD-M1):	1,296,766,129	1,082,320,866
Estimated CP + VSB (OD-M1):	117,567,192	58,377,609
Estimated Shot Count Reduction Ratio (OD-M1):	11.03	18.54

Excel spreadsheet already prepared and available for use for shot count analysis

Parameter entries are based on Design Specification

Shot Count Analysis report output includes shot count for VSB, CP+VSB, and provides the range of shot count reduction ratios. Use this as the shot count goal.

Shot Count Report Example



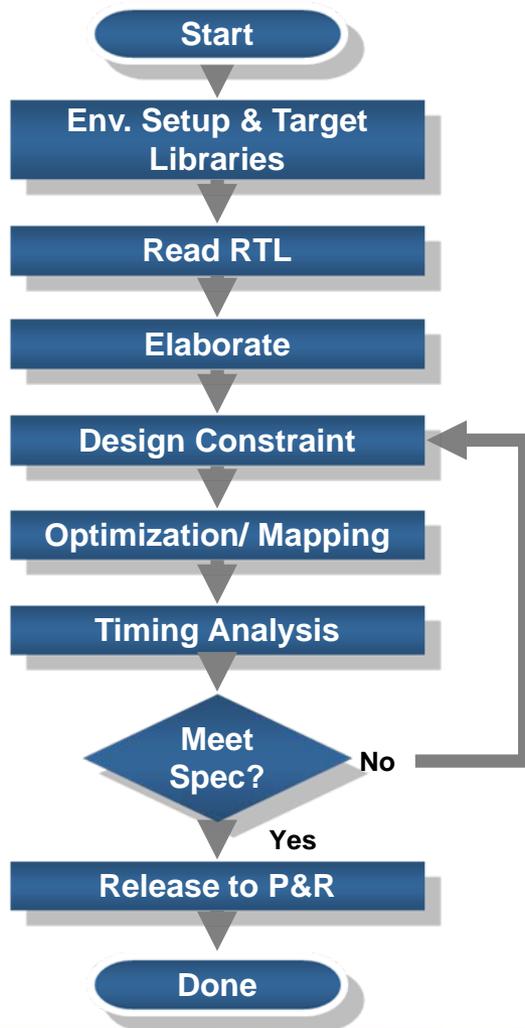
Model	Count	CP Shot	Total VSB Shots	Total DFEB Shots
-----	-----	-----	-----	-----
OAI22X6_D2S	6533	4	326650	26132
IVX1_D2S	20137	4	583973	80548
...				
SDFFRP_D2S	17461	8	5011307	139688
...				
-----	-----	-----	-----	-----
Total	320793		27138554	1681143

Reduction Reports

Shot Count Reduction Ratio (Cells): 16.14

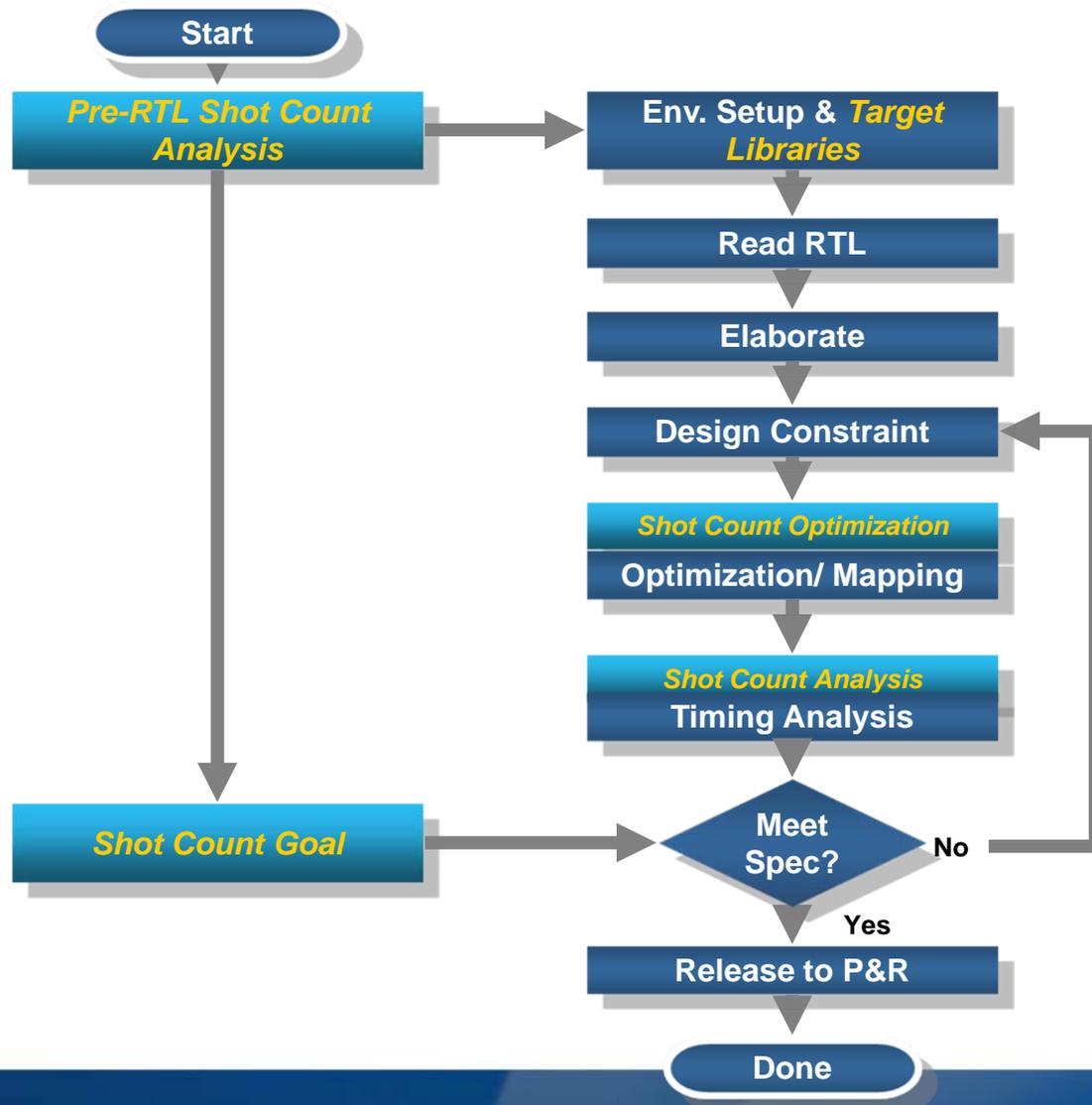
Synthesis Best Practices for DFEB

Generic Synthesis Flow



Generic RTL synthesis steps

DFEB Synthesis Flow



DFEB includes additional steps for shot count optimization and analysis

What Is NOT Changed



- No change to RTL
- No change to SDC constraint files
 - Same ECO refinement process used to get design to meet the Area, Timing, and Power.
- No change to timing analysis scripts or commands

DFEB Synthesis Steps

- Add DFEB overlay library to the target generic libraries

Otherwise the same as the generic synthesis tools setup

Import RTL Netlist and Elaborate



- Perform generic procedure to read in the RTL
- Elaborate the design
- Perform generic procedure to read in SDC constraints

Shot Count Optimization



- Prior to optimization and mapping, run shot count optimization setup script to set additional constraints to prefer DFEB overlay library cells
- Run generic optimization/mapping command to perform timing, area, and power optimization

Shot Count Analysis



- After optimization, run shot count analysis to:
 - Reset the cell attributes so that other reports are accurate
 - Generate a shot count report
- Compare the shot count reported to the shot count goal
 - Shot count analysis is based on cell count without taking wire routing, filler cells, and well taps in consideration
- Then run timing analysis and other reports

- Perform ECO to fix critical timing, area, or power issues with these in mind:
 - Based on DFEB constraints, virtually all cells will be DFEB overlay library cells
 - Where necessary, fix critical timing paths using non-DFEB (generic) cells with better performance at the cost of increased shot count

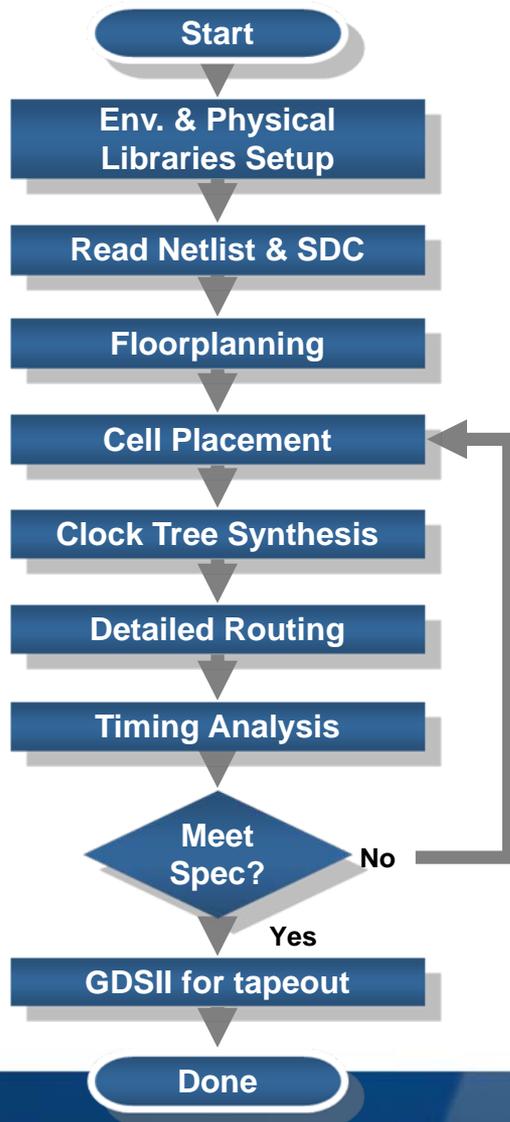
Release to Place & Route



- Release to place & route when timing, area, power and shot count goals are met
- Generate SDC for P&R tools as you would in generic flow

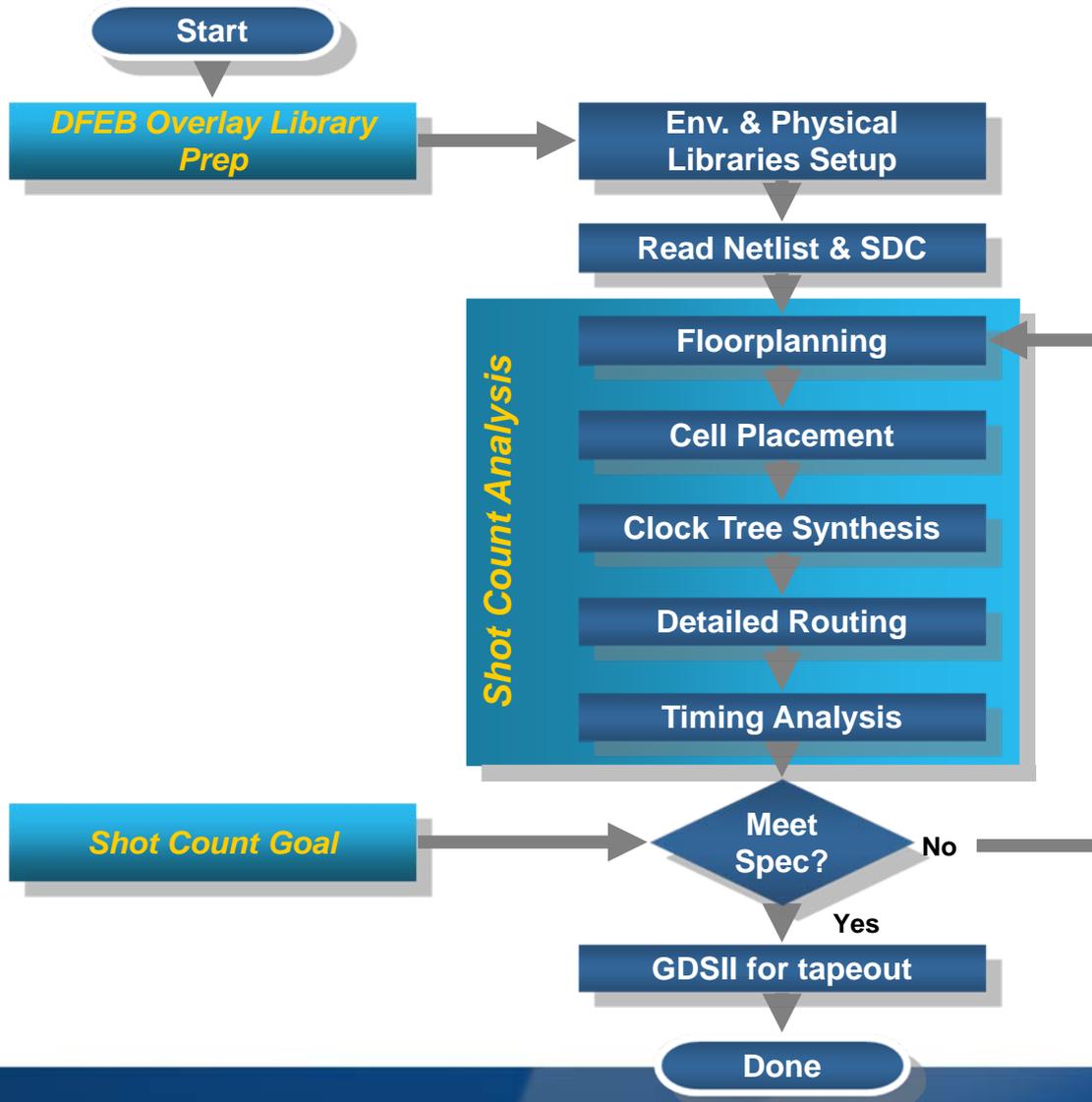
Place & Route Best Practices for DFEB

Generic Place & Route Flow



Generic Place & Route steps

DFEB Place & Route Flow



DFEB includes additional steps for shot count optimization and analysis

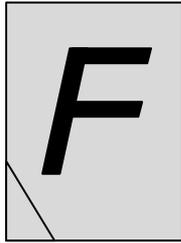
DFEB Overlay Library Preparation



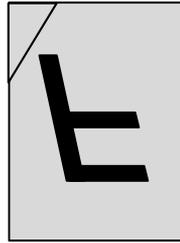
- Purpose: minimize shot count
- Set the following attributes in the DFEB overlay library to make them the default for the tools:
 - Orientation preference
 - Pin access and connection preference
 - Metal1 routing preference
- Can always override attributes if needed (to meet other constraints)

Orientation Preference

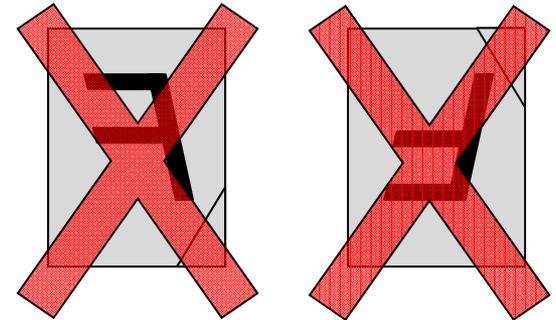
- North or Flip-South orientation is preferred for standard cells



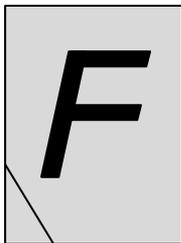
North (R0)



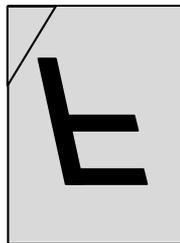
Flip-South (MX)



- North or Flip-South orientation is preferred for RAM/ROM macros



North (R0)

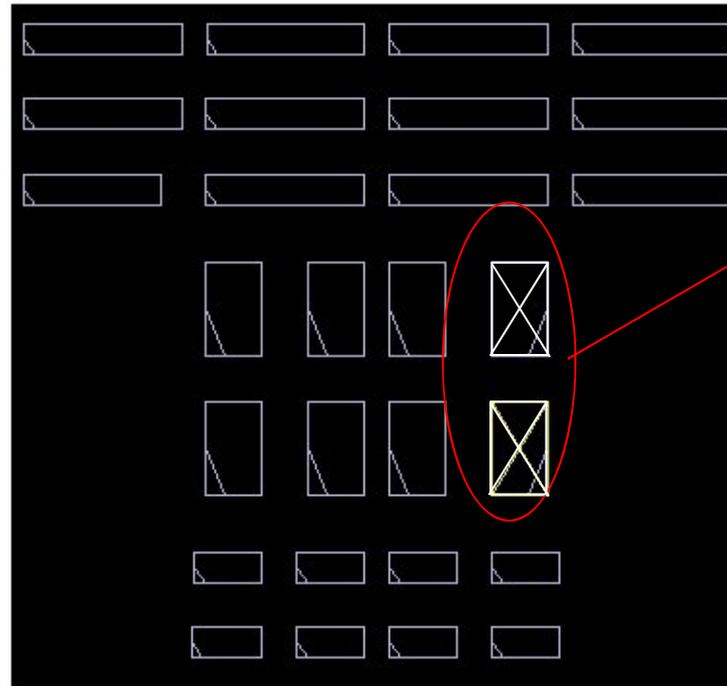


Flip-South (MX)

Shot count Warning:

Standard cells and RAM/ROM macros that do not follow the predefined orientations will be shot with VSB instead of CP, increasing shot count.

Floorplanning Examples



**Non-preferred
orientation for
RAMS.**

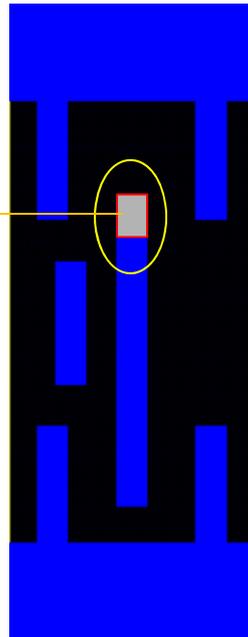
- RAMs with non-preferred orientation will be shot with VSB, and therefore increase the shot count.
- Trade off is between congestion and shot count.

Recommended:

Use non-preferred orientation only when needed to relieve routing congestion.

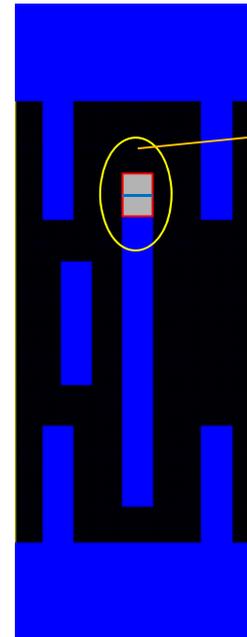
Pin Access and Via Drop Preferences

Enclosed via geometries completely inside standard cell pins



Preferred

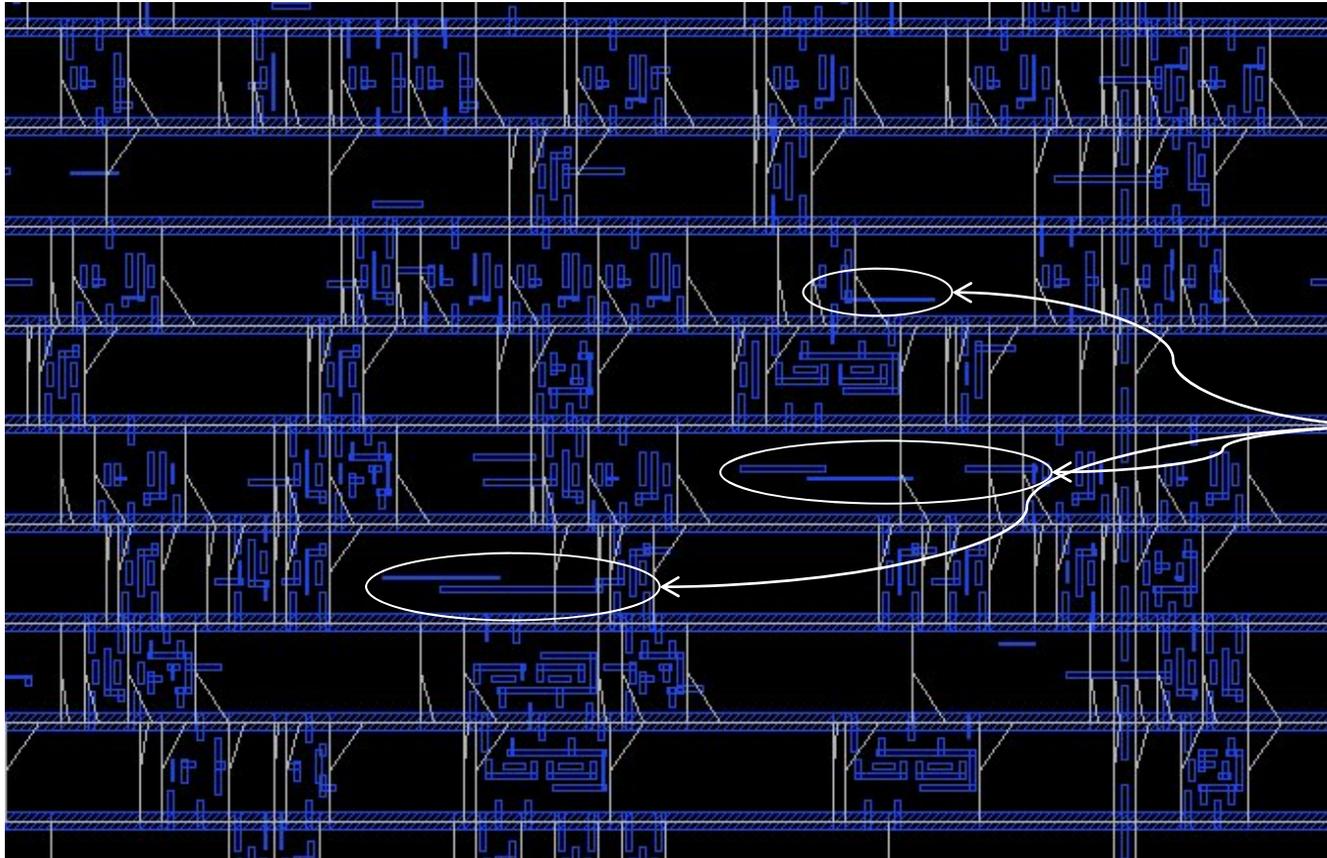
Enclosed via geometries extended outside the standard cell pins



**Not Preferred
(Extra VSB shots)**

- Refer to the P&R tools documentation for routing options to drop vias inside the standard cell pins

Metal1 Routing Preferences



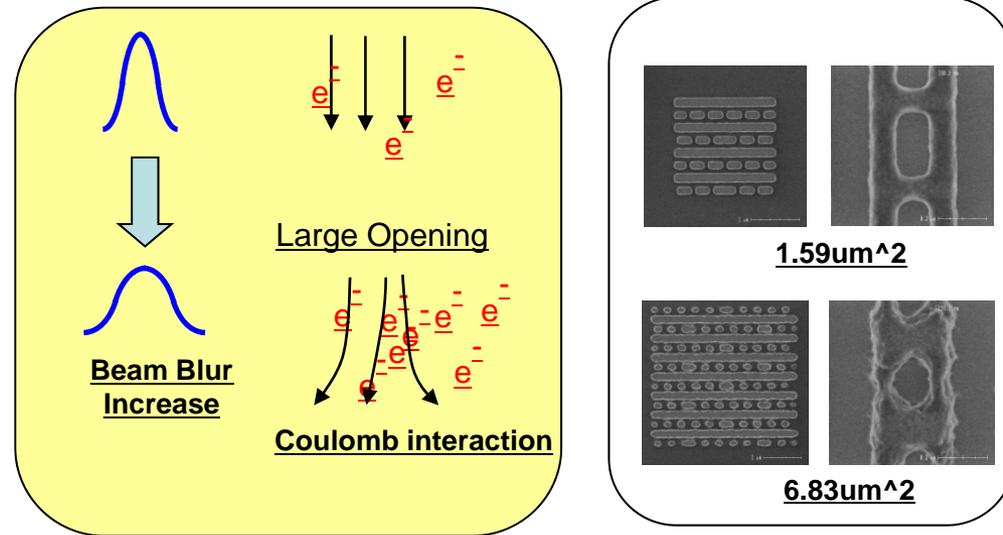
**Stub routes
and M1 routes**

- Metal1 stub routes will increase shot count

Shot count Warning:

Avoid Metal1 Stub Routing (Use tools option to turn off these types of routing)

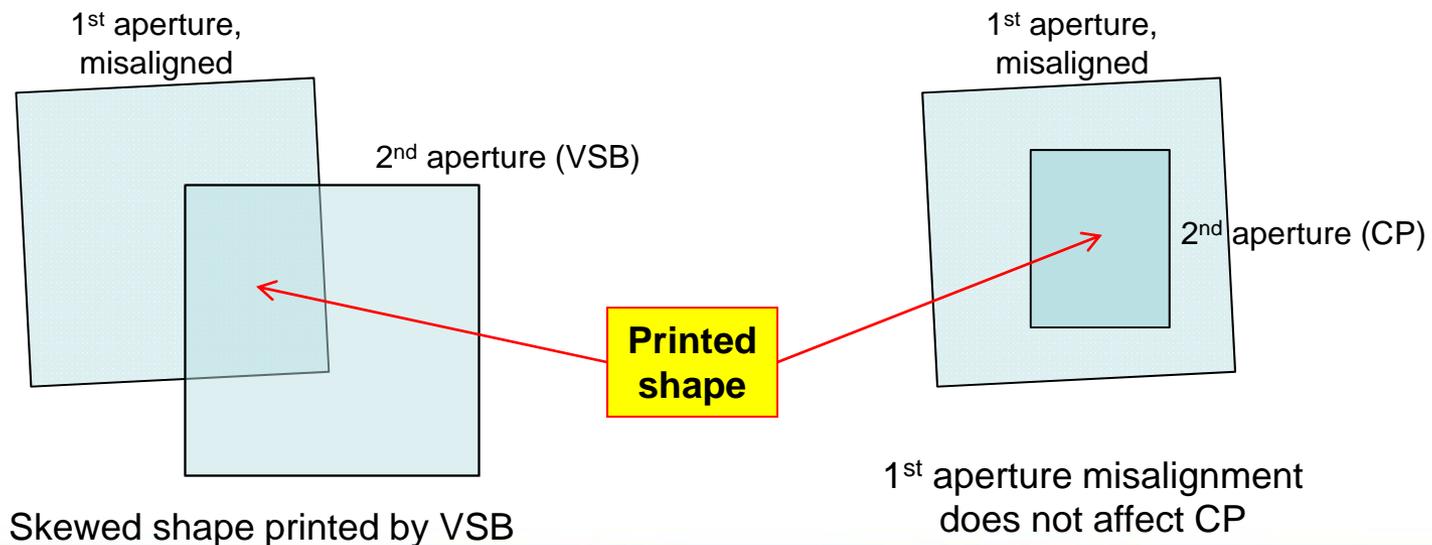
A Bit of Background



- Electrons in an e-beam repel each other
- As an e-beam becomes larger, printed image gets more blurred (see picture on right)
- Using close to maximum allowed e-beam size is important for less shot count.

Power Routing Has High Impact on Shot Count

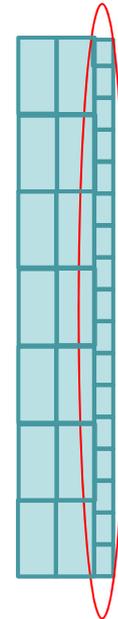
- Power routing is a very large area
- The Coulomb effect dictates the maximum area per shot
- CP can write wires longer than $2\mu\text{m}$ more accurately than VSB
 - Due to possible misalignment of first and second apertures for VSB
 - CP relies on the shape of the stencil alone



Power Grid Planning Using Wide Metals



14 CP shots
(Preferred)

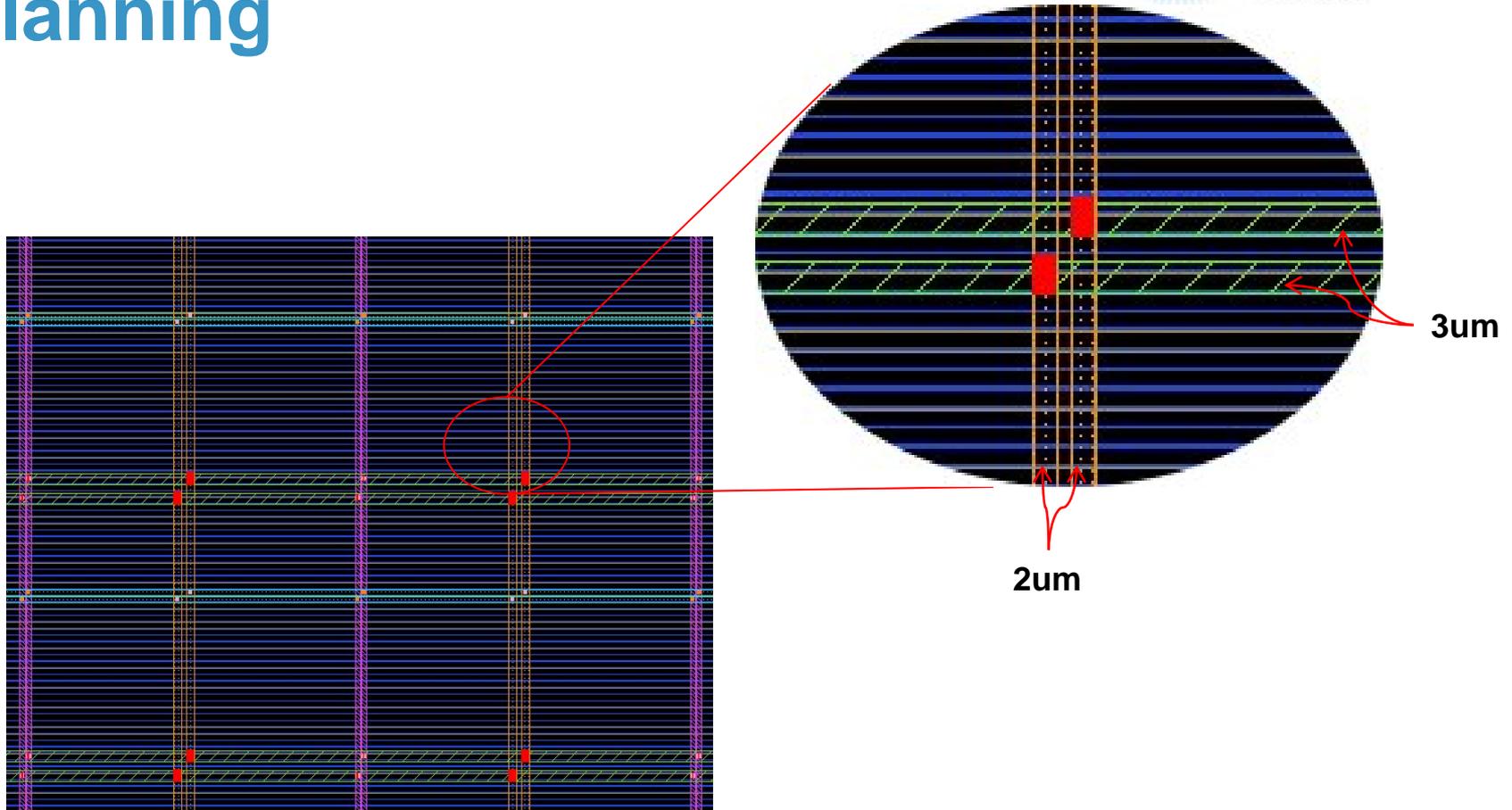


Extended area is shot using VSB

14 CP shots + VSB shots
(Avoid)

- Choose a unit width, and use whole multiples of this width
- Fewer, wider power stripes result in lower shot count

Example of Power Grid Planning



- Wide metals have widths of 2µm and 3µm (whole multiples of 1µm)

Cell Placement



- Perform generic cell placement step
- Shot count analysis after this step produces shot count report excluding shot count used for routing layers.

Clock Tree Synthesis (CTS)



- Specify buffers, inverters, and delay cells from the DFEB overlay library
- Perform CTS using the above DFEB cells
- Shot count analysis will now include the clock tree cells

Detail Routing and Timing Closure

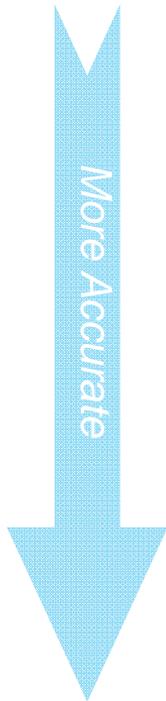


- Perform generic detailed routing step for timing closure
 - No M1 for routing
 - Via1 placed within a pin
 - For compatibility to photo-mask manufacturing, plan to do DFM design also
- Shot count analysis will now include the detail routing

Shot Count Analysis Accuracy



Shot count reports are refined in each step



Pre-RTL shot count analysis	Excel spreadsheet-based analysis. Parameter entries are based on design specification.
After synthesis	Shot count based on synthesis netlist
After power routing	Shot count includes power routing
After placement	Shot count includes cell sizing, buffer insertion, and well taps
After clock tree synthesis	Shot count includes clock tree buffers and inverters
After detail routing	Most accurate shot count report. Includes routing and filler cells.

DRC and LVS



- Perform generic DRC and LVS steps
- Export final GDSII for tape-out

Summary



- DFEB flow and DFEB overlay library enable EbDW IC manufacturing
- DFEB design methodology includes few additional steps for shot count optimization and analysis
- Shot count analysis throughout the flow monitors shot count and design trade offs
- DFEB design methodology is largely the same as a generic cell-based design methodology
- DFEB designs are fully compatible and can be manufactured with optical lithography for volume production

Summary of Abbreviations



CP	Character Projection
DFEB	Design for E-Beam
EbDW	E-beam Direct Write
VSB	Variable Shape Beam



Beam
Initiative